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PATENT APPLICATION

ATTORNEY DOCKET NO. 100201346-5

IN THE
UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s): James Stasiak et al

Confirmation No.:

Application No.: Unassigned

Examiner: Rao, Shrinivas H

Filing Date: Sep 22, 2003

Group Art Unit: 2814

Title: Nanometer-Scale Semiconductor Devices And Method Of Making

Commissioner for Patents

PO Box 1450

Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

This Information Disclosure Statement is submitted:

(X) under 37 CFR 1.97(b), or
(Within three months of filing national application; or date of entry of national application; or before mailing date of first office action on the merits; whichever occurs last)

() under 37 CFR 1.97 (c) together with either a:
() Statement under 37 CFR 1.97(e), or
() a \$180.00 fee under 37 CFR 1.17(p), or
(After the CFR 1.97 (b) time period, but before final action or notice of allowance, whichever occurs first)

() under 37 CFR 1.97 (d) together with a:
() Statement under 37 CFR 1.97(e)(1) or (2), and
() a \$180.00 fee set forth in 37 CFR 1.17(p).
(Filed after final action, a notice of allowance, on or before payment of the issue fee)

Please charge to Deposit Account 08-2025 the sum of \$0.00. At any time during the pendency of this application, please charge any fees required or credit any overpayment to Deposit Account 08-2025 pursuant to 37 CFR 1.25.

(X) Applicant(s) submit herewith Form PTO 1449 - Information Disclosure Citation together with copies, of patents, publications or other information of which applicant(s) are aware, which applicant(s) believe(s) may be material to the examination of this application and for which there may be a duty to disclose in accordance with 37 CFR 1.56.

() A concise explanation of the relevance of foreign language patents, foreign language publications and other foreign language information listed on PTO Form 1449, as presently understood by the individual(s) designated in 37 CFR 1.56 (c) most knowledgeable about the content is given on the attached sheet, or where a foreign language patent is cited in a search report or other action by a foreign patent office in a counterpart foreign application, an English language version of the search report or action which indicates the degree of relevance found by the foreign office is listed on form PTO 1449 and is enclosed herewith.

It is requested that the information disclosed herein be made of record in this application.

(X) I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, Alexandria, VA 22313-1450. Date of Deposit: 9/24/2003
OR

Respectfully submitted,

James Stasiak et al

By Donald J. Coulman

Donald J. Coulman

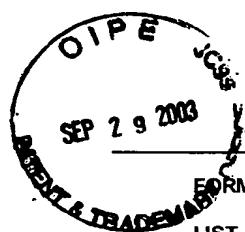
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Signature: Donald J. Coulman


PATENT APPLICATION

Sheet 1 of 1

FORM PTO-1449
**LIST OF PATENTS AND PUBLICATIONS FOR
APPLICANT'S INFORMATION DISCLOSURE
STATEMENT**

(Use several sheets if necessary)

ATTY. DOCKET NO.	APPLICATION NO.	CONFIRMATION NO.
100201346-5		
APPLICANT		
Jam s Stasiak, et al		
FILING DATE	GROUP	
Sept 22, 2003	2814	

REFERENCE DESIGNATION
U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	PUBLICATION DATE	NAME	Pages, Columns, Lines Where Relevant Passages or Figures Appear
1A				
1B				
1C				
1D				
1E				
1F				
1G				
1H				
1I				
1J				
1K				

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	PUBLICATION DATE	NAME OF PATENTEE OR APPLICANT	Pages/Columns/Lines Where Relevant Passages/Figures Appear	Check if Translation attached
1L					
1M					
1N					
1O					
1P					

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

1Q	Otto-M et al. "Characterization and application of a UV-based imprint technique" Microelectronic Engineering (Netherlands), vol 57-58, pages 361-6, September 2001.
1R	Beck-M et al., "Improving nanoimprint Lithography stamps for 10nm features", Proceedings of the 2001 1st IEEE Conference on Nanotechnology, IEE-Nano 2001, pages 17-22, 2001.
1S	

EXAMINER

DATE CONSIDERED